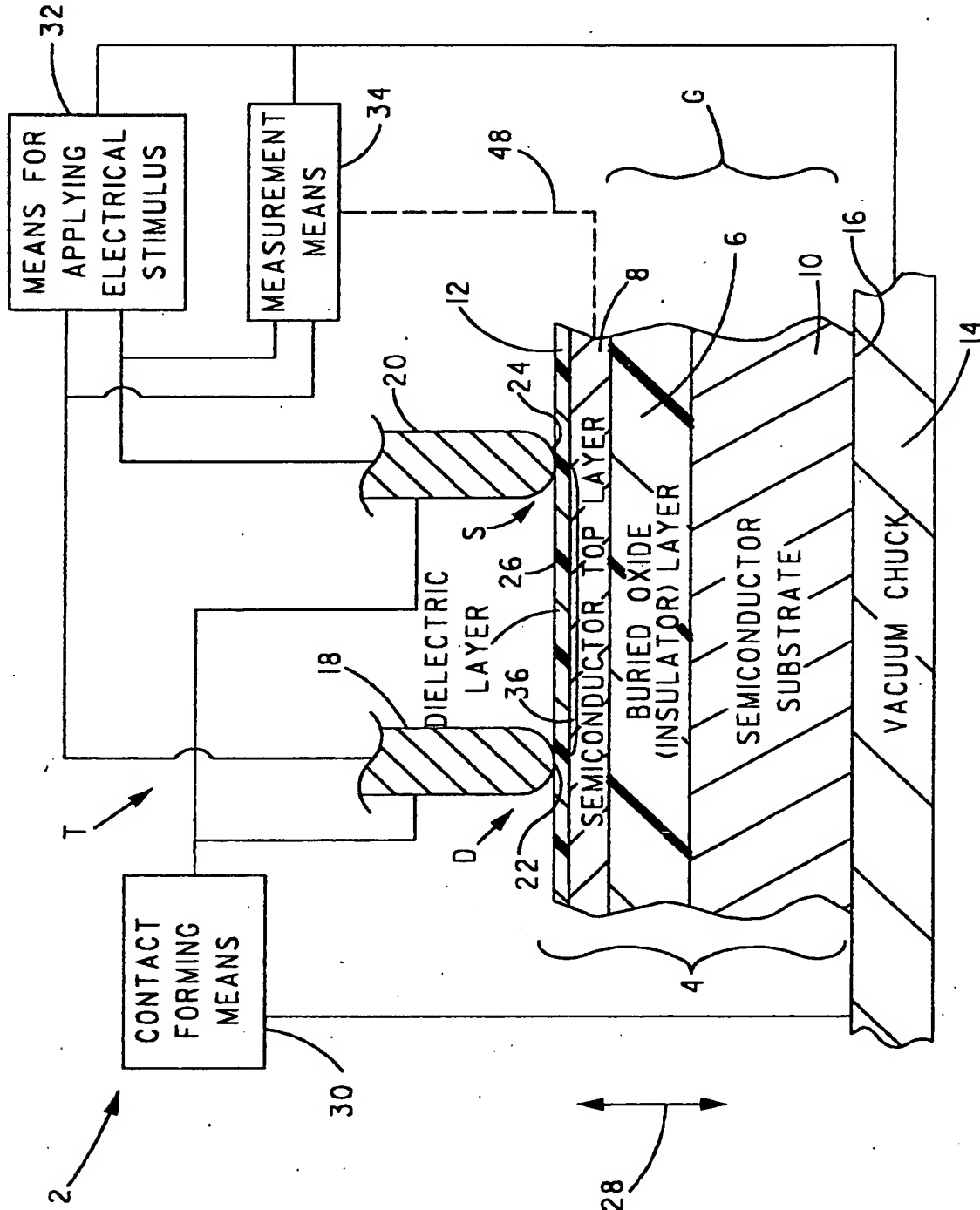


"METHOD OF ELECTRICAL CHARACTERIZATION OF A SILICON-ON-INSULATOR (SOI) WAFER"

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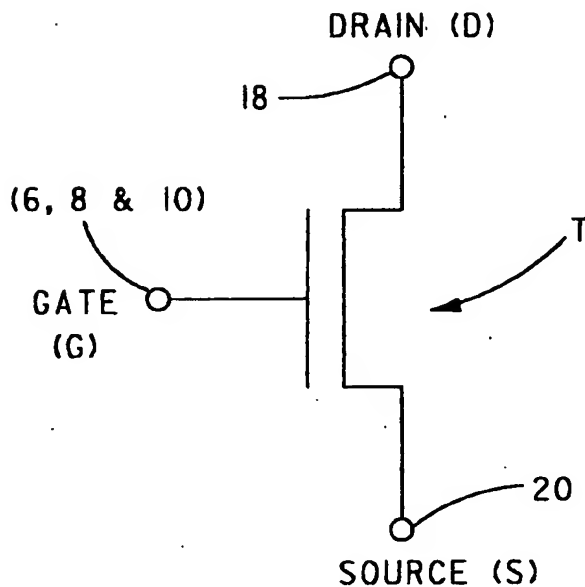


FIG. 2

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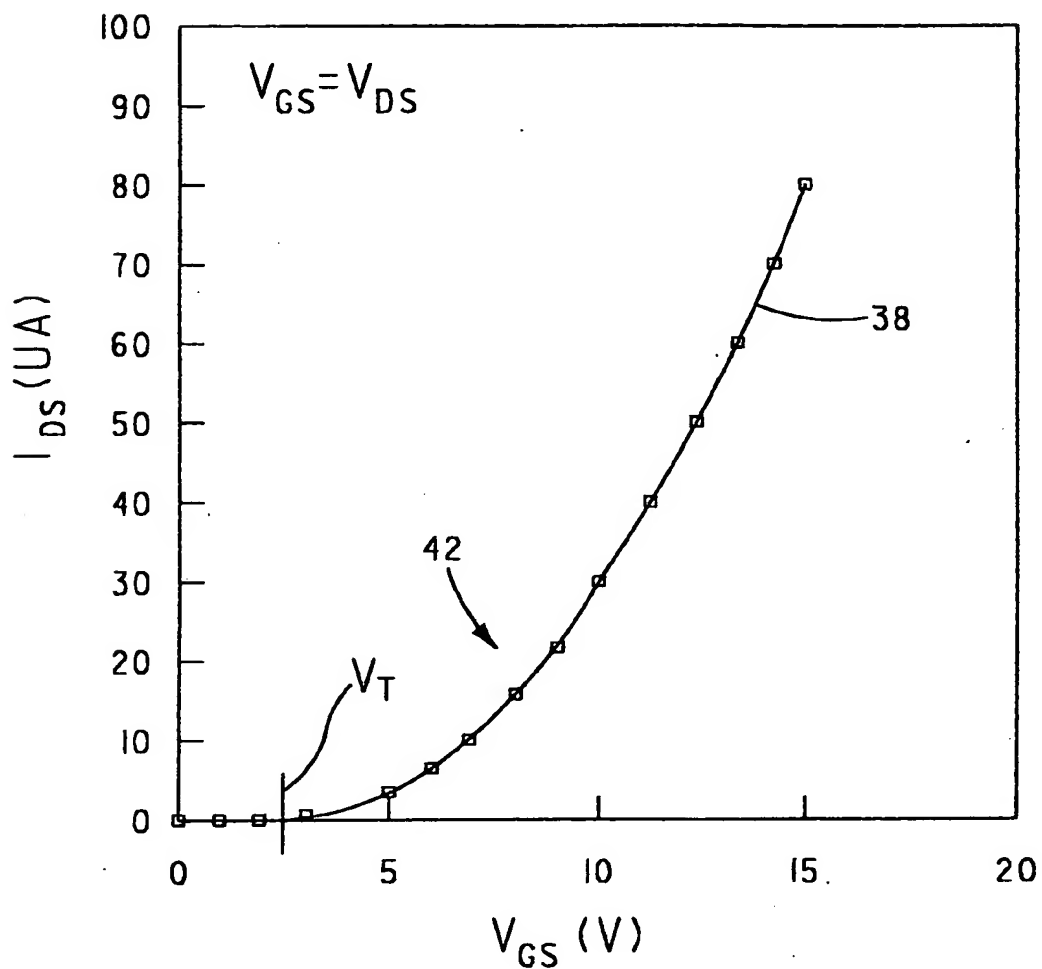


FIG. 3

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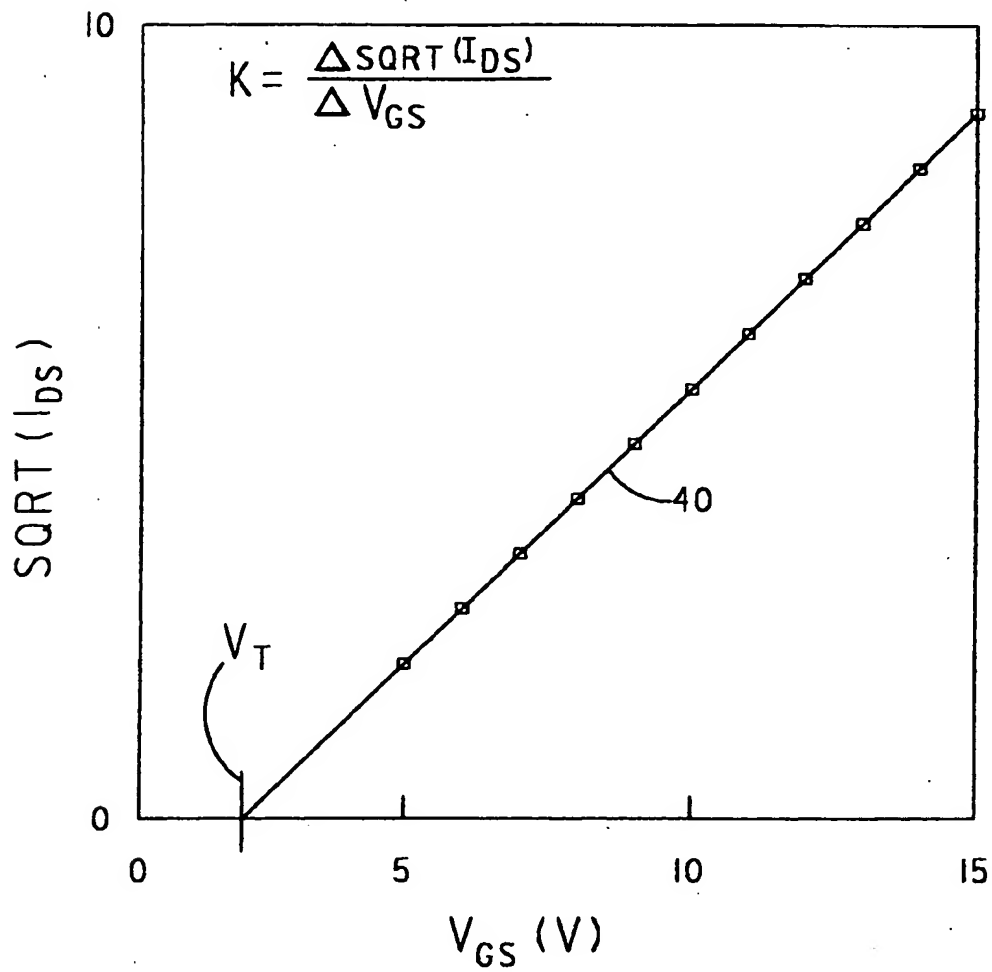


FIG. 4

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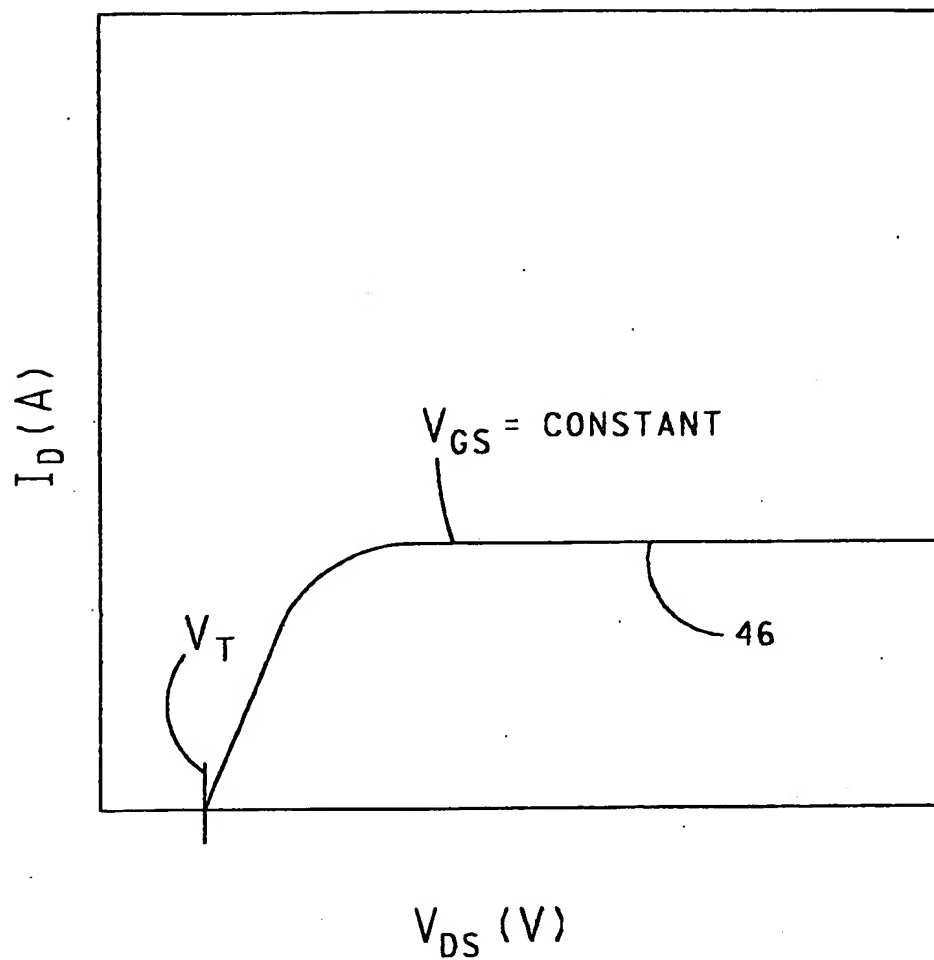


FIG. 6

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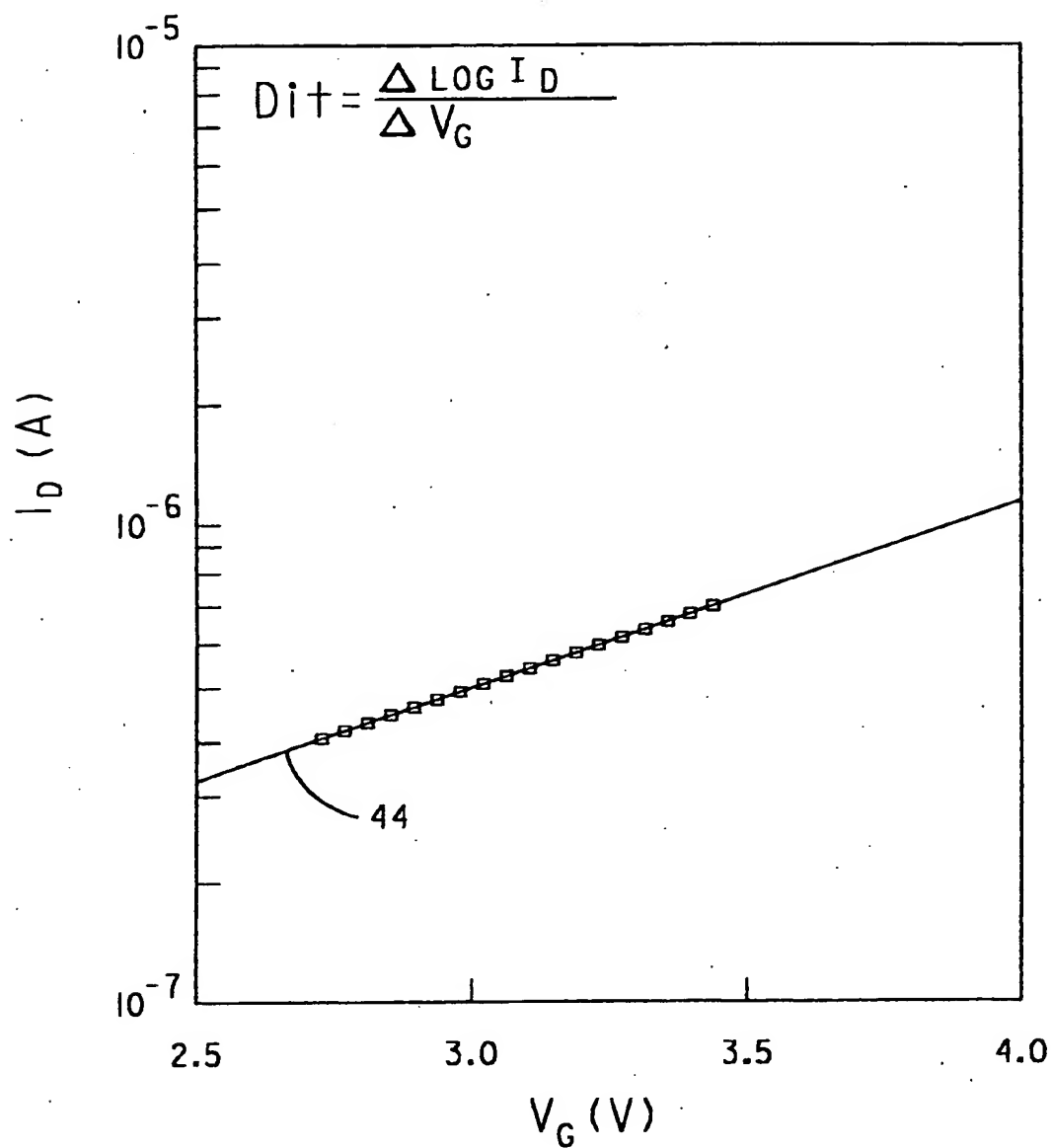


FIG. 5